*List of Patents and Publications For Applicant's Information Disclosure Statement (Use several sheets if necessary)				ATTY. DOCKET NO. AMDI:133\HON			SERIAL NO. 10/790,939			
				APPLICANT Akif Sultan et	APPLICANT Akif Sultan et al.			CERTIFICATE OF MAILING 37 C.F.R. 1.8 I hereby certify that this correspondence is being deposited with the U.S. Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, Virginia 22313-1450 on the date below: 1		
				FILING DATE March 1, 2004			GROUP		£.	
				U.S. PAT	ENT	DOCUM	ENTS	3		·
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